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(Revised 07/	/2007)			Application Number	10/583,570	
INFOD	MATION	DISCLO	CLIDE	Filing Date	March 5, 2007	
1				First Named Inventor	DeSimone	
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Examiner	Date	
Signature	Considered	

^{*}Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Substitute for form 1449/PTO (Revised 07/2007)				Complete if Known		
				Application Number	10/583,570	
INFOD	NA A TYAN	TOPCEO	CHIDE	Filing Date	March 5, 2007	
	INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)			First Named Inventor	DeSimone	
1				Art Unit	1791	
((Examiner Name	Not Yet Assigned	
Sheet	10	of	10	Attorney Docket Number	035052/338899	

		OTHER DOCUMENTS	
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	English Language Translation Attached
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